

Special Issue

Metasurfaces: Design, Fabrication and Applications

Message from the Guest Editors

Metasurfaces, artificial structures consisting of periodic sub-wavelength units, offer versatile platforms for light control and intrigue various novel phenomena and applications in physics, material science, chemistry, biology, and energy. Metasurfaces not only introduce revolutions of optical elements but also provide unprecedented opportunities for micro-/nano-cavities for light-matter interactions, which are essential for the development of electronic-photonics integrated circuits and quantum information devices. Notably, the thriving study of metasurfaces is building on the remarkable progress of nanophotonic simulation and nanofabrication techniques. In this Special Issue, we would like to cover the new design theory and methods of metasurfaces, the development of nanofabrication strategies to realize targeted nanostructures and nanopatterns, and the promising applications based on the metasurfaces. For this Special Issue, we aim to collect the top research and prospects for fundamentally understanding, fabricating, engineering, and developing novel applications of metasurfaces and stimulate new ideas and directions in the related fields.

Guest Editors

Dr. Shikai Deng

Dr. Rui Ma

Dr. Lei Chen

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Micromachines
Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
micromachines@mdpi.com

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Editor-in-Chief

Prof. Dr. Ai-Qun Liu

Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China

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